



Our Docket No: 42P10058

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
)	
Han-Ming Wu et al.)	Examiner: Nguyen, Hung
)	
Serial No: 09/752,938)	Art Unit: 2851
)	
Filed: December 29, 2000)	
)	
For: Purging Gas from a)	
Photolithography Enclosure)	
Between a Mask Protective)	
Device and a Pattern Mask)	
)	

PRELIMINARY AMENDMENT

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Prior to examination of the present application, please enter the following amendments and consider the following remarks.

FIRST CLASS CERTIFICATE OF MAILING

I hereby certify that I am causing the above-referenced correspondence to be deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and that this paper or fee has been addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

September 23, 2003

Date of Deposit

Krista Mathieson

Name of Person Mailing Correspondence

Krista Mathieson

Signature

September 23, 2003

Date